

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Won et al.

Serial No.: To be assigned

Filed: Currently herewith

For: METHODS OF FORMING RUTHENIUM FILM BY CHANGING PROCESS
CONDITIONS DURING CHEMICAL VAPOR DEPOSITION AND RUTHENIUM
FILMS FORMED THEREBY

Date: March 15, 2004

Mail Stop PATENT APPLICATION
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to the examination of the above-referenced application, please enter the following amendments below. Applicants provide the present Preliminary Amendment pursuant to the rules stated in revised 37 C.F.R. 1.121 that became effective on July 30, 2003.